

## Mooney, Michael

Start: Sat 1/10/04 9:00 AM  
End: Sat 1/10/04 9:30 AM

Recurrence: (none)

BRS 199 ((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and SiO\$6 USPAT; US-PGPUB 2004/01/07 11:14 0

BRS 536 ((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon) USPAT; US-PGPUB 2004/01/07 11:15 0

BRS 172 (((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6)) USPAT; US-PGPUB 2004/01/07 11:40 0

BRS 48 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and (optic\$6 with (ax\$6 or port))) USPAT; US-PGPUB 2004/01/07 11:18 0

BRS 35 ((((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and (optic\$6 with (ax\$6 or port))) and cavit\$6 USPAT; US-PGPUB 2004/01/07 11:36 0

BRS 66 sacrificial with etch-stop USPAT; US-PGPUB 2004/01/07 11:35 0

BRS 22 (((((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and (optic\$6 with (ax\$6 or port))) and cavit\$6) and (sacrificial with layer\$6) USPAT; US-PGPUB 2004/01/07 11:41 0

BRS 48 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with cavit\$6) USPAT; US-PGPUB 2004/01/07 11:53 0

BRS 788 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) USPAT; US-PGPUB 2004/01/08 15:11 0

BRS 25 (((((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with cavit\$6)) and (sacrificial with layer\$6) USPAT; US-PGPUB 2004/01/07 11:54 0

BRS 77 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) USPAT; US-PGPUB 2004/01/08 14:42 0

BRS 34 (((((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6 with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser))) and (sacrificial with layer\$6) USPAT; US-PGPUB 2004/01/07 14:22 0

BRS 1 "20020168136" USPAT; US-PGPUB 2004/01/07 17:59 0

BRS 1 5986796.pn. USPAT; US-PGPUB 2004/01/07 18:14 0

BRS 1 "20020168136" and (support with port) USPAT; US-PGPUB 2004/01/07 18:18

0  
BRS 1 5986796.pn. and (mirror same etch\$6) USPAT; US-PGPUB 2004/01/07 18:33  
0  
BRS 1 "20020168136" and (etch-stop with optic\$6) USPAT; US-PGPUB 2004/01/07 21:23  
0  
BRS 1 "20020168136" and (etch\$6 with coat\$6) USPAT; US-PGPUB 2004/01/07 21:23  
0  
BRS 0 5986796.pn. and (etch\$6 with coat\$6) USPAT; US-PGPUB 2004/01/07 21:22  
0  
BRS 0 5986796.pn. and (etch\$6 with coat\$6) and (etch\$6 with \$6stop) USPAT; US-PGPUB  
2004/01/07 21:22 0  
BRS 1 "20020168136" and (etch\$6 with coat\$6) USPAT; US-PGPUB 2004/01/07 21:23  
0  
BRS 1 "20020168136" and (etch-stop with optic\$6) USPAT; US-PGPUB 2004/01/07 21:47  
0  
BRS 1 ("20020168136" and (etch\$6 with coat\$6) ) ("20020168136" and (etch-stop with optic\$6) )  
("20020168136" and (etch\$6 with \$6stop)) USPAT; US-PGPUB 2004/01/07 21:24 0  
BRS 1 "20020168136" and (device near1 layer) USPAT; US-PGPUB 2004/01/07 21:26  
0  
BRS 1 "20020168136" and (etch\$6 with \$6stop) USPAT; US-PGPUB 2004/01/07 21:28  
0  
BRS 1 "20020168136" and (coat\$6 with optic\$6) USPAT; US-PGPUB 2004/01/07 21:47  
0  
BRS 33 (((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6  
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6  
with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) and ((dielectric\$6 with (film or  
coat\$6)) same thick\$6) USPAT; US-PGPUB 2004/01/08 14:48 0  
BRS 31 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6  
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6  
with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) and ((dielectric\$6 with (film or  
coat\$6)) same thick\$6)) and metal USPAT; US-PGPUB 2004/01/08 14:49 0  
BRS 26 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6  
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6  
with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) and ((dielectric\$6 with (film or  
coat\$6)) same thick\$6)) and (metal with (coat\$6 or layer\$6)) USPAT; US-PGPUB 2004/01/08 14:52  
0  
BRS 14 (((((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6  
orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)) and optic\$6 and (SiO\$6 or silicon)) and (dielectric\$6  
with (film or coat\$6))) and ((mirror or reflect\$8) with (cavit\$6 or filter or laser)) and ((dielectric\$6 with (film or  
coat\$6)) same thick\$6)) and (metal with (coat\$6 or layer\$6) with (reflect\$6 or mirror\$3)) USPAT; US-PGPUB  
2004/01/08 14:53 0  
BRS 5 (coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 orfabricat  
\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7) USPAT; US-PGPUB 2004/01/08  
15:21 0  
BRS 22 (MEMS or Moems) and (dop\$6 with curvature) USPAT; US-PGPUB 2004/01/08 15:22  
0  
BRS 19 ((MEMS or Moems) and (dop\$6 with curvature)) not ((coat\$6 with layer\$6) and (MEMS or  
MOEMS) and ((process or method) with (mak\$6 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and  
(dop\$6 with curv\$7)) USPAT; US-PGPUB 2004/01/08 15:22 0